

Notice of References Cited	Application/Control No. 10/811,932		Applicant(s)/Patent Under Reexamination YUE ET AL.	
	Examiner Elias Desta		Art Unit 2857	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-2005/0071039	03-2005	Mitrovic, Andrej S.	700/121
*	B	US-2004/0267399	12-2004	Funk, Merritt	700/121
*	C	US-2005/0221514	10-2005	Pasadyn et al.	438/014
*	D	US-6,853,920	02-2005	Hsiung et al.	702/1
*	E	US-6,587,744	07-2003	Stoddard et al.	700/121
*	F	US-6,249,712	06-2001	Boiquaye, William J. N-O.	700/31
*	G	US-5,940,299	08-1999	Choi et al.	700/121
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)			
	U	Mozumder et al., 'A Monitor Wafer Based Controller for Semiconductor Processes', August 1994, IEEE Publication, Vol. 7, No. 3, pages 400-411			
	V	Patel et al., 'Adaptive Optimization of Run-to-Run controllers: The EWMA Example', February 2000, IEEE Publication, Vol. 13, No. 1, pages 97-107			
	W	Del Castillo et al., 'An Adaptive Run-to-Run Optimizing Controller for Linear and Nonlinear Semiconductor Processes', May 1998, IEEE Publication, Vol. 11, No. 2, pages 285-295			
	X	Paramore, 'simple Curve Fitting', May 3, 2002, pages 1-4			

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.